Linac4 H⁻ Ion Source Work Package

The numerous contributions of the Linac4 ion source and sLHC teams and international colleagues is gratefully acknowledged

Abstact

Linac 4 IS design parameters: 100^{*}+400 μs, 80 mA H⁻ pulses at 45 kV, Repetition rate: 1-2 Hz, Emittance 0.25 πmmmrad

Status of the linac 4 ion source:

An RF driven volume source (copy of the DESY 35 kV, H⁻ source) is operated at the 3 MeV test stand.

The commissioning at 35 kV has been completed.

July 2010: Electron dump problems encountered during the upgrade to 45 kV.

The source is converted to a 45 kV proton source used for the RFQ and chopper commissioning until April 2012.

August 2010: Crash program initiated to provide a new Linac4 source design.

SLHCPP EU-project: 50Hz, 1.2 ms, 100kW, 2MHz RF plasma Generator designed, produced and tested. Test stand is operational.

(*) pre-pulse of 100 μ s to neutralize space charge.

Linac4 WPIS outline

- 2005-July 2010
 - Survey of possible ion source
 - Copy of the DESY drawings
 - 2007, 95 kV and 45 kV design
 - 2008, Production of a Volume source
 - 2009, Commissioning at 35 kV
 - 2010, Commissioning at 45 kV
- Aug-2010 –June 2011
 - Analysis of the commissioning findings
 - Proposition of a draft WPIS amendment
 - Decision to produce and H⁻ ion source test stand and to include Cesiation
 - Review of accelerator H⁻ ion sources; outcome:
 - Baseline is RF driven H⁻ ion source
 - Magnetron H⁻ ion source as backup to be launched asap.
 - March 2011: WPIS vs. shutdown (LS1) schedule
 - Staged approach, 30, 50, 80 mA
 - 30 mA, 45 kV H⁻ source on the 3 MeV test stand by mid 2012 !
- Plasma Generator test stand operation:
 - Staff training, vacuum, gas injection
 - Prototype RF-Plasma parameters measurement & plasma diagnostics validation

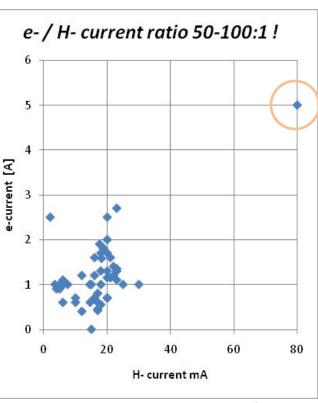
A radio frequency driven H⁻ source for Linac4, Rev. Sci. Instrum. **79, 02A504 2008**

ENGINEERING PARAMETERS FOR DIAGNOSTICS FOR A SOURCE TEST LINE FOR LINAC 4, https://edms.cern.ch/document/953231/0.1

3 MeV test stand: Commissioning findings 7/2010-8/2011

- Electron-dump energy
 - e/H⁻ from 20 to 100
 - 5 Amps @ 45 kV → 225 J/ms/mm²
 - 2 orders of magnitude reduction is mandatory
- High voltage
 - Sparks (2 μF @ 45 kV \rightarrow 2 kJ)
 - Antenna air ionization
 - Internal capacities (sparks to H₂-line)
- Temperature stability
- Alignment, tuning flexibility
- Spare parts policy (*fast IS-exchange*)
- Emittance is nominal at low current (expected to increase at nominal current)
- Electron to H⁻ ratio (collar-front plate tuning)
- HT power supply requires upgrade for 2 Hz operations
- 3D beam transport simulation mandatory

After solving e-dump issue, It is worth to complete the 45 kV commissioning of a volume source.





DESY vs. Linac4 ion source parameters

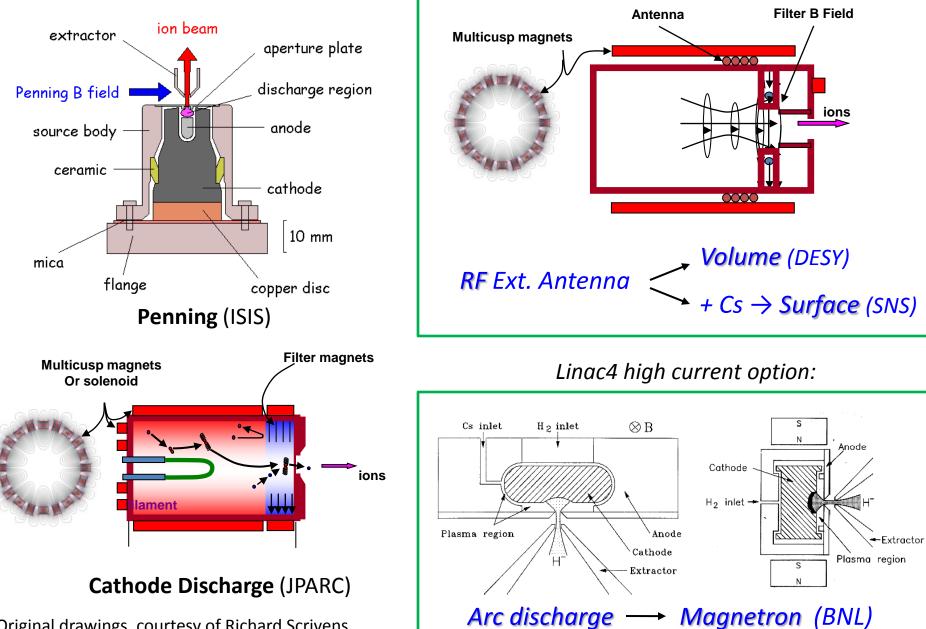
H⁻ ion source stages		DESY	Linac4 July-2010	Linac4 Nominal	L4-nom / DESY
Repetition rate	Hz	6		2	
HT	kV	35	35	45	128%
RF-power	kW	30	30	100	333%
RF-pulse	J	4.5	15	70	15.56
H- current	mA	30	20	60-80	267%
Pulse duration	ms	0.15	0.5	0.7	467%
Emittance	πµm	0.25	0.25	?	
Co-extracted electrons	А		2	5	
e-dump energy	J		35	158	

Strategy for ISWP:

- Systematic analysis of all physical processes is mandatory !
- Simulation will be validated by specific measurements
- Linac4 ISs will have limited life time, they will evolve and needs to be swiftly exchangeable.
- Cesiation must be considered, learned and integrated (reduction of e/H⁻ ratio)
- Spare IS and new IS-prototypes will be tested off-line (IS-test stand acceptance procedure),
- Linac4: on-line conditioning &commissioning of ion sources mandatory.

H⁻ Sources for Linacs

Linac4 baseline:



Original drawings, courtesy of Richard Scrivens.

Cesiated H⁻ ion sources,

Data extracted for specific operation conditions on: Cs-injection rate, H⁻ current, emittance, HV, repetition rate and life time

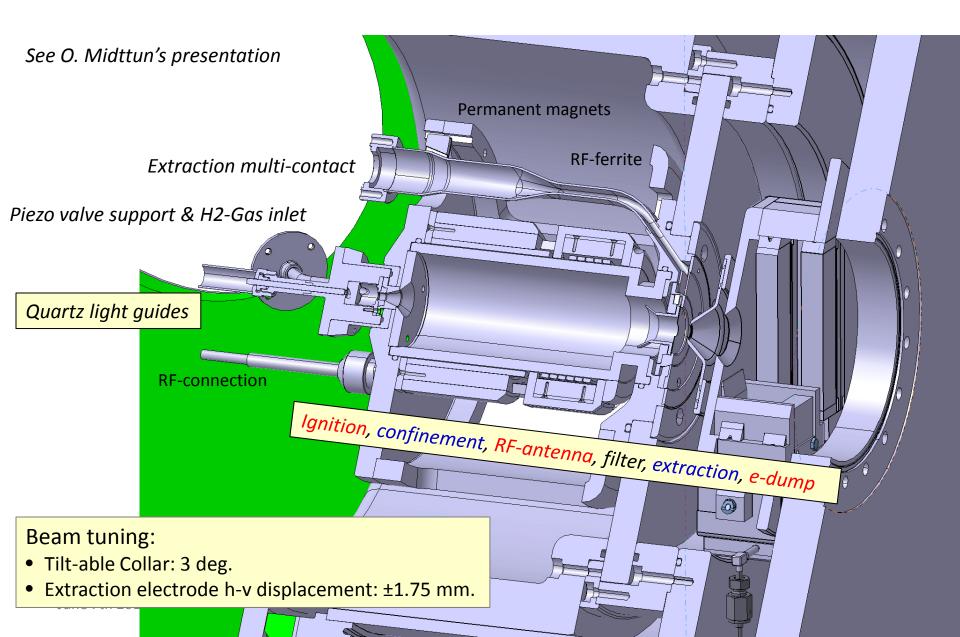
	Cs consumption	mg/day	H ⁻ current, pulse duration, emittance and extraction voltage	Rate, Life time
LANL	20 g / 30 days	600	40 mA, 1000 <i>μs, 0.13 πμ</i> m, 80 keV	120 Hz,
DESY		0	25 mA, 150 <i>μs, 0.25 πμ</i> m, 35 keV	6 Hz, 6 month
J-parc LaB6, W	tested	0 >0	36 mA, 500 <i>μs, 0.25 πμ</i> m, 50 keV 60 mA	25 Hz, 500 h
SNS Goal:	30 mg / 40 days 3 mg	<0.75 <0.1	56 mA (after RFQ), 1000 <i>μs, 0.2 πμ</i> m, 65 keV	60 Hz, 5 weeks
RAL	3 g/month	100	35-80 mA <i>,</i> 800 <i>μs, 0.3 πμ</i> m, 65 keV	50 Hz, 1 month
BNL	< 0.5 mg/h	< 12	90-100 mA, 700 <i>μs, 0.4 πμ</i> m, 35 keV	6 Hz, 3-9 month

Cesiated IS operation must be demonstrated on the test stand prior to on-line operation !

Outcome of accelerators H⁻ ion sources review Feb. 2011

- Review of world's accelerators H⁻ ion sources completed (Feb)
 - RAL-ISIS
 - BNL Magnetron + Cs metal
 - JPARC
 - SNS inductive RF internal or external antenna + Cs Chromate
 - DESY inductive RF external antenna
- **No** H⁻ ion sources within specified emittance @ 45kV & nominal beam intensity !
- Choices for Linac4:
 - 1) L4-inductive external antenna (volume source) + Cs (surface source)
 - > 1 MCHF already invested
 - Existing know how, intrinsic flexibility
 - 2) Upgrade of BNL's magnetron to 45 kV as nominal current option and Risk mitigation
 - Simple and reliable for BNL operations @ 35 kV, 6Hz
- Summary:
 - August 2010 ISWP resource envelope accepted as 0-baseline.
 - Pulsed extraction & BNL-IS Mitigation added to the 0-baseline
 - Cesiated RF and Magnetron need R&D, learning & demo phase

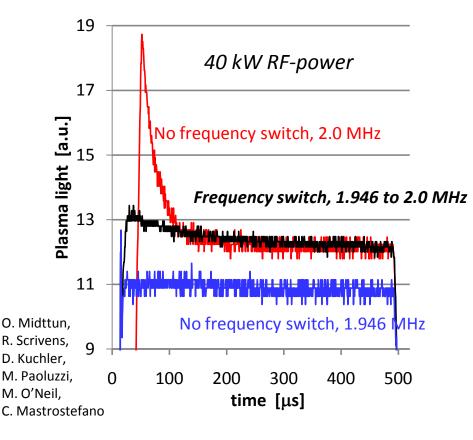
Linac4 H⁻ source; copy of DESY's IS



Linac4-IS Volume source:

Plasma light driven RF frequency switch

- Optimum coupling without and with plasma.
- Reduces jittering of ignition time
- Improves current stability



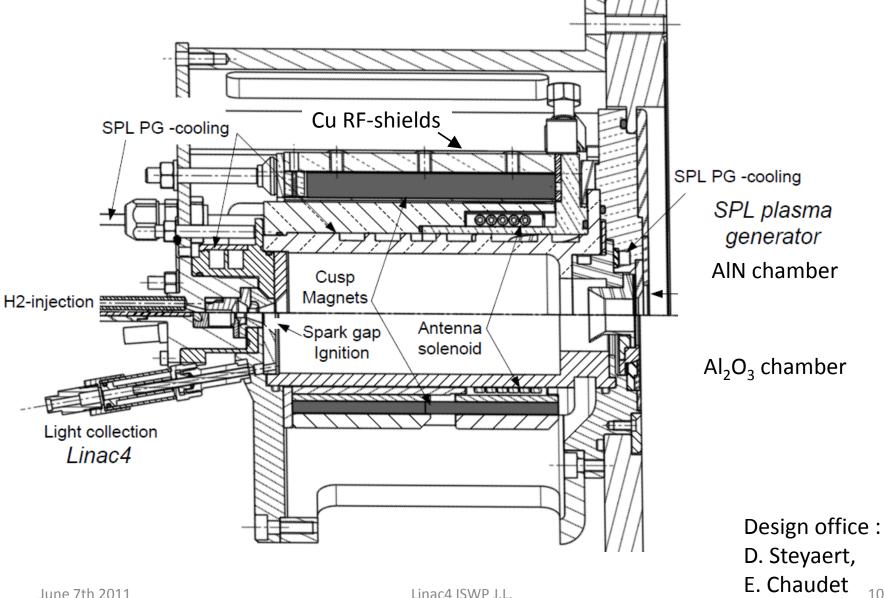
Mandatory parallel tasks:

- IS-R&D + simulation
- 3 MeV tests
- IS Front end design
- IS Test stand production

Making use of exiting equipment; -**Volume source** kept for 3 MeV commissioning as p-source - 20-30 mA H⁻ volume source provided following upgrades :

- The e/H⁻ ratio is kept under control (measurement and modelling)
- The dump vaporization issue is solved (modelling the electron surface energy flux and secondary electrons and pulse HV-supplies)
- Modelling the magnetic field, electrode displacement and tilt to understand electron and H⁻ beam alignment features.
- 1) Stable ignition

SPL plasma generator as H⁻ volume source



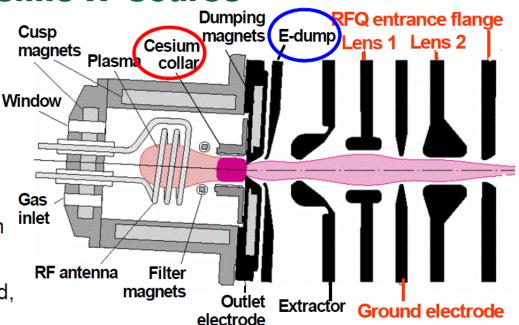
SNS H⁻ ion source, RF internal antenna

Cs-chromate + Al-Zr getter

The SNS Baseline H⁻ Source

LBNL developed the SNS H⁻ source, a cesium-enhanced, multicusp ion source.
Typically 250 W from a 600-W, 13-MHz amplifier generate a continuous low power plasma.

•The high current beam pulses are generated by superimposing 30-70 kW from a pulsed, 80-kW, 2-Mz amplifier.



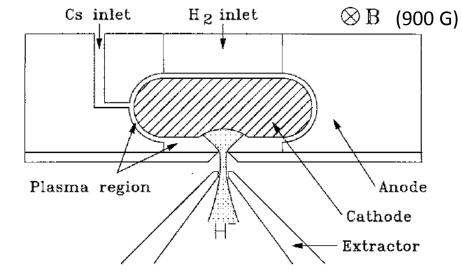
•After significant modifications, the SNS H⁻ source now routinely produces the 38 mA LINAC beam current required for 1-1.4 MW beams! •The source service cycle has been increased from 2 weeks in 2008, to 3, and to 4 and 5 weeks without seeing old-age signs or failures. •We have demonstrated 56 mA MEBT pulse current and 59 mA MEBT peak current, which is sufficient for 2-3 MW beam power.

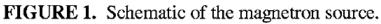
An initial injection of ~3 mg Cs is sufficient for Managed by UT->=5 FEW.eeks of persistent, ~50 mA H- beams.

BNL's Magnetron surface plasma H⁻ ion source

- Pulsed H₂ injection
- IS-exchange : 8h
- Life time: 6 month
- Slow buildup of CsOH will gradually block the hydrogen inlet

TABLE 1. Typical ru	inning parameters
H- current	90-100 mA
J (H-)	1.5 A/cm^2
Extraction voltage	35 kV
Electron/H-	0.5-1.0
Arc voltage	140 - 160 V
Arc current	8 - 18 A (see note)
Rep rate	7.5 Hz
Pulse width	700 µs
Duty factor	0.5%
rms emittance	$\sim 0.4 \pi \text{ mm mrad}$
Cs consumption	< 0.5 mg / hr
Gas flow	~ 2 sccm







Ref: Performance of the Magnetron H- Source on the BNL 200 MeV Linac , James G. Alessi,

20th ICFA Advanced Beam Dynamics Workshop on High Intensity and High Brightness Hadron Beams, edited by W. Chou, Y. Mori, D. Neuffer, and I.-F. Ostiguy, 2002

Mandatory R&D for best Linac4 IS-candidates

function	RF-source	BNL Magnetron
Pulsed gas injection	R&D	R&D
Pulsed HT power supplies	R&D	R&D
Pulsed discharge	Ignition, 20A, 1 kV + R&D on uncorrelated ignitions	Discharge, 400-150 V, 15A, R&D
Cesium injection	Cs-Chromate Single injection	Cs-metal cw flow
H-plasma	Inductive coupling, ignition	Cs-Mo-H plasma & metallurgy
Life time extrapolated to L4	5 weeks, 60 Hz > 3 years	6 month, 6 Hz > 1.5 years
Risks , mitigation	60 to 1-2 Hz, thermal control, commissioning time	6 to 1-2 Hz, heating
Tuning	RF pulse and frequency Gas pressure	Arc power, Gas pressure
Extraction	Multistage 65 kV to 45 kV	Single 35 kV to multi 45 kV, e-dump
Dump & min e/H ⁻	3D transport	3D & Increased energy

Both system require very similar development at CERN:

- Pulsed power supplies
- Thermal control, Cs-ovens
- 3D Simulation of H⁻ extraction & e-dump June 7th 2011
 Linac4 ISWP

Test stand & front end design: Compatible to RF & Magnetron sources and to the SPL PG or DESY-IS

WPIS H⁻ Ion source: staged approach

	Volume source	Surface source	Magnetron
Operational experience H ⁻ current	DESY 30 mA	SNS 50 mA	BNL 80 mA
Plasma Heating process	2 MHz RF Ext. antenna	2 MHz RF Int. & Ext. antenna	Arc discharge
Cesiation		Cs-chromate Single deposition:	Cs metal Constant flow
Cs-Oven test stand		Nov. 2011	Nov. 2011
Electron / H ⁻ ratio	10-100	10	0.5 - 1
357 Plasma test stand (operational)	\rightarrow Sept. 2012	2013	2014-2015
3MeV test stand (until Dec-2012) (operational, Bldg. 152)	Jul. 2012- Dec- 2012	2012	2014
IS test stand (Bldg. 357)		2013	2015
Linac4, buiding 400	March 2012	Oct 2013	Mar 2015

Challenges being addressed – Review presentations

- Design, production
 - Front end
 - Plasma generators & extraction
 - LEBT, beam diagnostics
 - Vaporization of e-dump, Electron to H⁻ ion ratio
 - Ab initio simulation vs. observables, Emittance
 - Pulsed power supplies
 - Pulsed gas injection, vacuum
 - Safety
- Commissioning
 - RF-coupling, Plasma characterization
 - High Voltage sparks
 - Impurities
- Operation
 - Graphical user interface
 - Plasma monitoring and diagnostics
 - Stability, Temperature control
 - Beam tuning and alignment
- Identification of Life time limiting processes
 - Antenna ageing
 - Plasma driven abrasion

D.Steyeart, G. Favre

R. Scrivens, *T. Zickler*, *J.-B.* Lallement *U.* Raich

T. Kalvas, O. Midttun, H. Pereira

D. Nisbet, D. Aguglia P. Chiggiato

M. Kronberger, M. Wilhelmsson

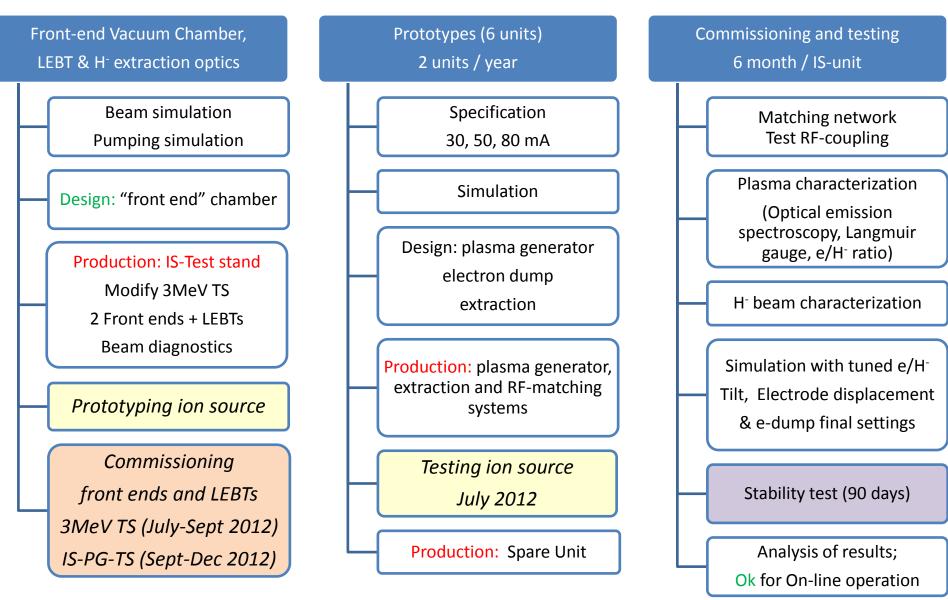
M. Paoluzzi, C. Schmitzer

I. Kozsar, G. Bellodi, M. O'Neil

WP Overview:

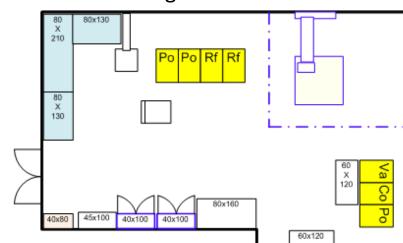
L4-Milestones :

July 2012 H- tests at 45 keV @3 MeV-TS January 2013 Move into L4 building



357-R-005; Plasma and Ion source

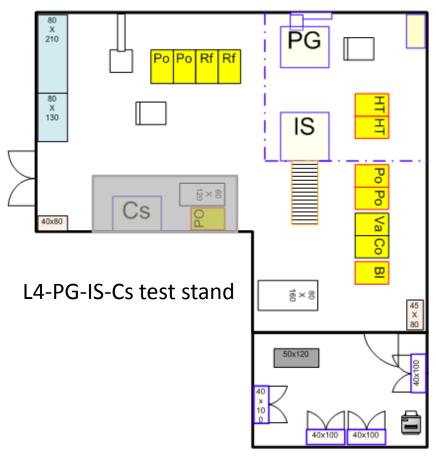
Demineralized Water cooling and SPL RF-generator



sLHC-PG test stand

- Mass spectrometer
- 3d Magnetic field measurement system
- Optical spectrometer Phototube and filters
- Langmuir gauge

Missing space and not suited for Cs-lab Challenging handling of equipment Integration study required + Cs-transport under inert gas + access to CERN's chemical lab



-80

X 130

> 45 X 80

х

160

10.5 m

х

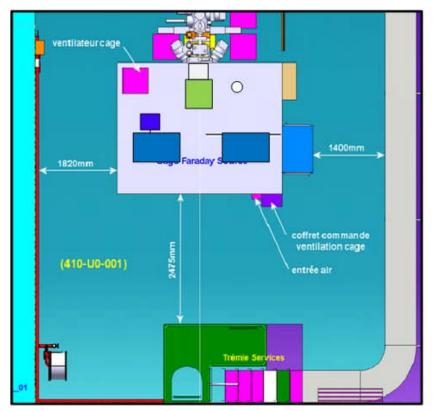
120

40x100

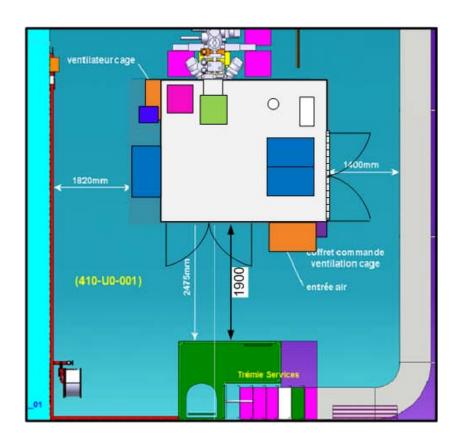
80x80

Faraday cage

3MeV test stand Faraday cage (origin: 95 kV layout)

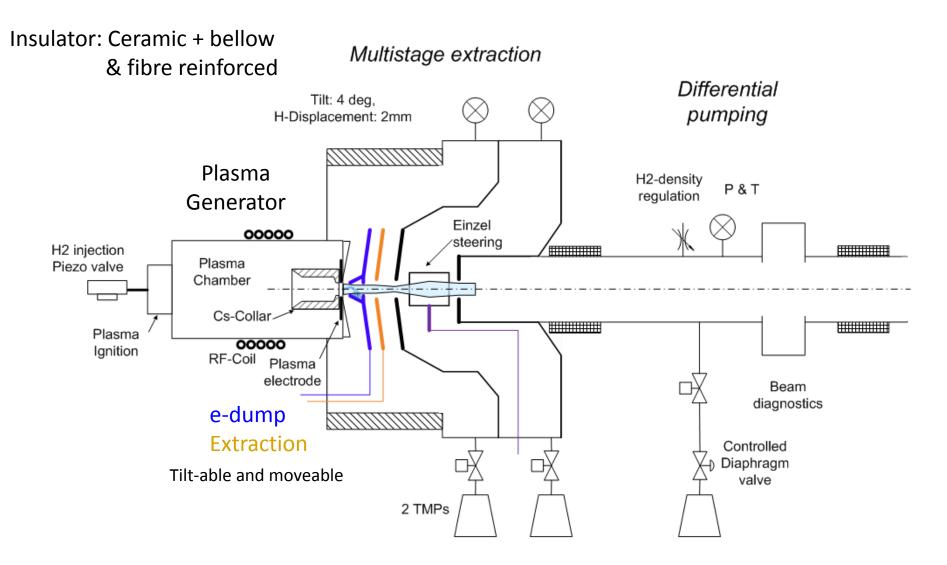


Linac4 Faraday cage Gain in accessibility mandatory to host pulsed HV-transformers and for "fast" ion source exchange

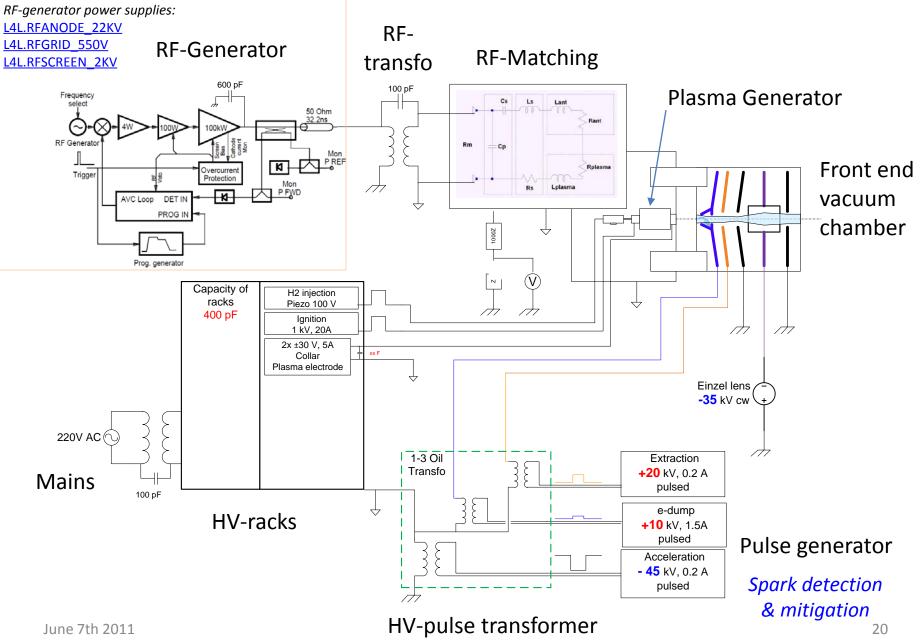


H2 gas system out of HV cage and common to LEBT and IS

Diff. Pumping, Insulator, Tilt and Alignment



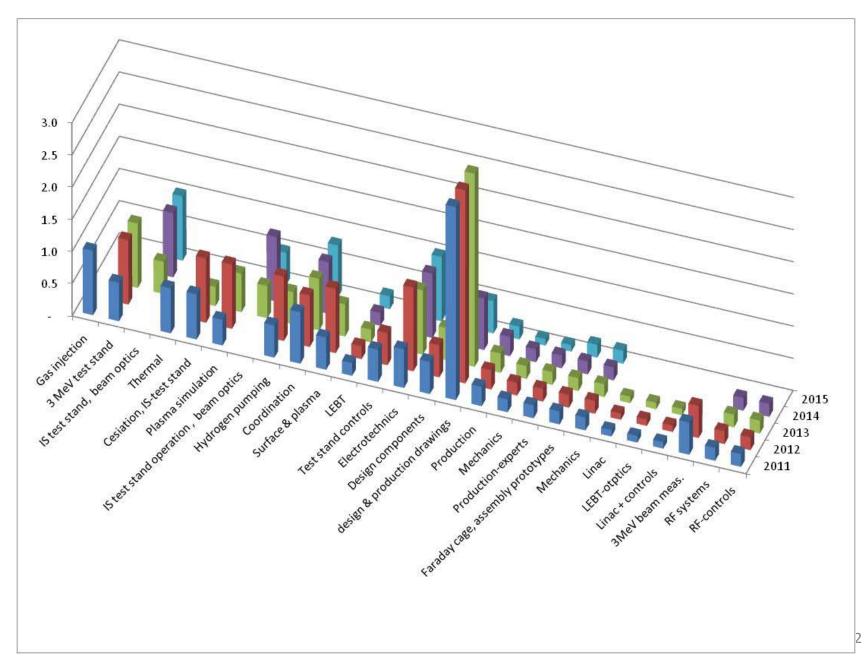
WPIS Power supplies



WP-Linac4 ion sources: Teams involved

Group	L4-WP	Staff FTE	Fell. FTE	kCHF	Task description
DGS-SSE	1.3				Safety standard
EN-MME	1.5				Design, integration, production
BE-ABP	2.1				Faraday cage, Ion source & LEBT, Beam optics, Specification, Tests, alignment, monitoring and safety systems, GUI, production
EN-MEF	2.1				Gas distribution systems (H2, Ar, N2)
BE-RF	2.6	1.5		290	Design, operation and maintenance of the RF systems
BE-BI	2.7				Beam Instrumentation, design and production
TE-MSC	2.9				Magnets, magnets supports, production
TE-EPC	2.10				Pulsed HV and Magnet Power supplies
TE-VSC	2.11				Design of vacuum & pumping systems, pumping simulation, LEBT density regulation
BE-CO	2.12				Controls, timing, maintenance of GUI
ISWP	total :				

Manpower distribution

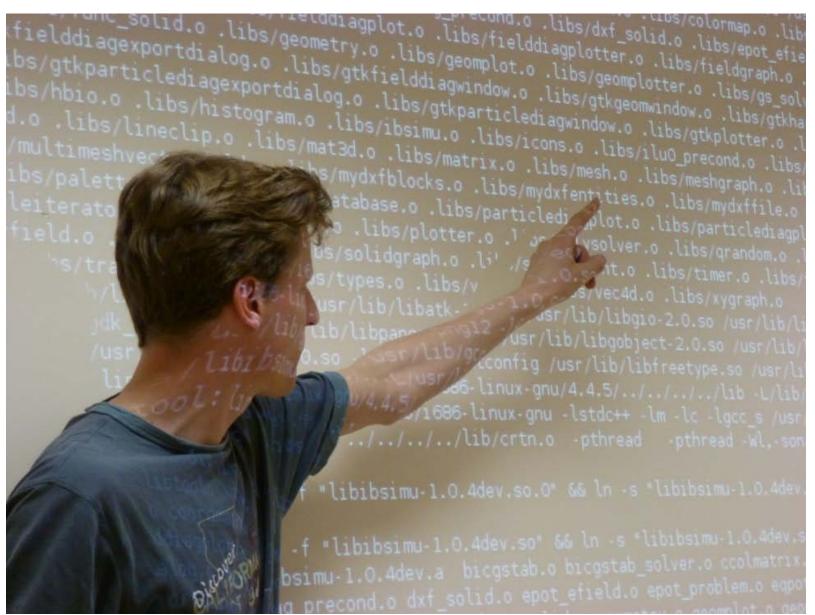


Collaborations, sLHC & linac4 IS

Creative manpower was required to address missing staff and expertise; Fellows, PhDs & Project associates and collaboration to external institutes the list below is our way to address it.

- SNS M.P. Stockli: Visit J. Lettry to SNS (April), Operation and GUI, IS-conditionning, ion source exchange of external, internal antenna plasma Generators (SNS linac and test stand)
- IPP Garching (*sLHC*): Seminar U. Fantz at CERN,
 - Visit J. Lettry, M. Kronberger (February):
 - Visit Cs-laboratory and ITER ion source
 - Emission spectroscopy and Cs-density diagnostics
 - Interpretation of emission spectroscopy via CR models
- Rutherford Appleton Laboratory, ISIS ion source
 - Visit D. Faircloth December (eddy current shielding), february-March high power operation of SPL plasma Generator
 - Visit J. Lettry to RAL (January), ion source operation and exchange, new test stand.
 - Arc discharge plasma simulation (John Adams Institute)
- Prof. Akiyoshi Hatayama, (KEIO university, Japan)
 - Simulation of e-heating in Hydrogen plasma, undefined schedule, upgrade from arc discharge to external antenna.
- S. Mochalskyy (Orsay & Cadarache), 3D-simulation of the plasma in the CERN linac4 ion source (Plasma parameter measurement pending).
- O. Tarvainen &T. Kalvas(University of Jyvaskyla) *sLHC & Linac4*
 - UV-VUV Lyman lines emission spectroscopy on sLHC plasma. 2 weeks plasma (*completed*).
 - T. Kalvas code for simulation of multistage extraction with co-extracted electrons (6 weeks lecture)
- BNL, James Alessi, visit R. Scrivens, F. Wenander and J. Lettry (Feb. Apr. 2011)
 - Operation, drawings

Ibsimu/libs/lecture/Taneli/



Sputtering and Mo-deposition under H2-vapours



SEM observations:

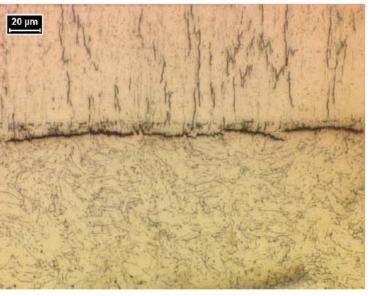
Cathode tip: sample 2 section analysis

EN Engineering Department

RAL-penning cathode by Courtesy of D. Faircloth

Cs Sputtering of Mo epitaxial Mo-growth under H2 atm. Generation of brittle Mo-flakes





& Materials Engineering

WPIS Controls, Monitoring

Controls: Settings and readout of effective value

- Power supplies: All currents and voltages (time)
- RF Amplifier:
 - Power setting (time), frequency shift
 - Injected, reflected power
 - Current and voltage phase, Power deposited into the plasma
- Plasma generator: OES-intensities: $H\alpha$, $H\beta$, $H\gamma$ (time)
- Gas injection, settings pulse (time), H2-Pressure
- Vacuum: Pressure of differential pumping tanks (time)
 H2 Density of LEBT
- Timing signals

Controls panel software by OP team not yet discussed but necessary

WPIS Beam diagnostics

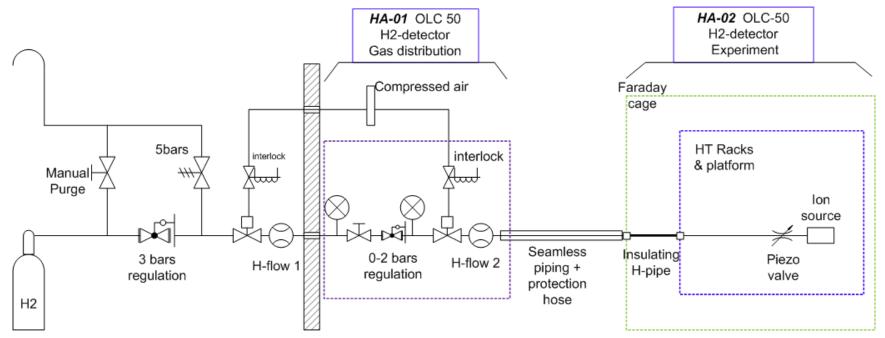
(schedule integration pending)

- Emittance meter
- Faraday cups, Beam current monitor
- x-y Beam profile monitor
- Beam energy (and plasma potential via Retardation method)

ID	Task Name	Total Cost
258	Beam Diagnostics 357	480 kCHF
259	Emittance meter (tuned for frequent use)	330 kCHF
260	Mechanics	250 kCHF
261	Electronics	80 kCHF
262	Faraday cups 357 (2 units floating up to 5 kV)	20 kCHF
263	Beam profile measurement (10x10 x-y meas grid)	80 kCHF
264	Retardation Beam energy	50 kCHF

H2 injection

M. Wilhelmsson



H- test stand at building 357 proposition:

The amount of explosive gas is minimized in the HT ion source set up as follow:

- 2 flow meters, 2 interlocked pneumatic valves
- OLC50 flammable gas detectors with hood on the low pressure gas distribution
- OLC50 flammable gas detectors with hood on the experimental area
- Seamless tubing up to the faraday cage
- Insulating tubing from the farday cage to the HT racks-platform

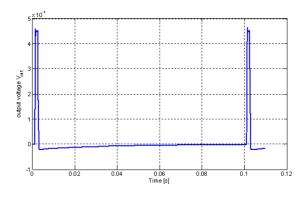
Interlock system : Presence of 10-20% LEL or H2 flow > nominal.

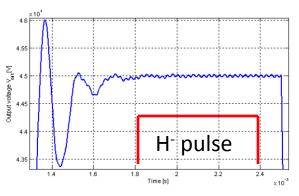
This shall also be considered for the *Linac4 ion source,* and merged with the Linac4 LEBT

D. Nisbet D. Aguglia

WPIS Power supplies

	Responsible		Voltage,	Load	load duration	Pulse duration	Rep. rate	357 test facility's test		3 MeV		Status			
n	Group	type	polarity	[A]	[ms]	[ms]	[Hz]	PG	Cs	IS	Linac4	Spares	total	avail.	need
Gnd + transfo	TE/EPC	R&D	-45 kV	0.2	0.7	2-5	2			1	1	1	3		3
Gnd + transfo	TE/EPC	R&D	20 kV	0.2	0.7	2-5	2			1	1	1	3		3
Gnd + transfo	TE/EPC	R&D	4 kV	2	0.7	2-5	2			1	1	1	3		3
Gnd	*	commercial								1	1	1	3	1	2
Gnd	TE/EPC	commercial	-40 kV	0.2	0.7	cw				1	1	1	3		3
HT-racks	BE/ABP	CERN	+/- 30 V			CW		1			1	1	3	2	1
HT-racks	BE/ABP	CERN	+/- 30 V			CW		1			1	1	3	2	1
HT-racks	BE/ABP	R&D	+1 kV	20	0.1	0.1	2	1			1	1	3	2	1
Gnd + transfo		R&D	400/150 V	20	1					1			1		1
HT-racks		R&D							1		1		2		2
HT-racks		R&D							1				1		1
Gnd	TE/EPC	commercial		350		cw				2	2	1	5		5
Gnd	TE/EPC	commercial		10		cw				4	4	1	9		9
Gnd		R&D			0.1					1	1	1	3		3
Gnd	TE/EPC	CERN	20 kV	2		cw				1	1	1	3	2	1
Gnd		CERN	-50 kV	0.05		cw				1	1		2	1	1
	ind + transfo ind + transfo ind + transfo ind ind T-racks T-racks T-racks ind + transfo T-racks T-racks ind + transfo T-racks ind - transfo ind ind ind	Groupind + transfoTE/EPCind + transfoTE/EPCind + transfoTE/EPCind*indTE/EPCindTE/EPCT-racksBE/ABPT-racksBE/ABPT-racksBE/ABPind + transfoTT-racksImage: Comparison of the transfoT-racksTind + transfoTE/EPCind + transfoTE/EPCindTE/EPCindTE/EPCindTE/EPCindTE/EPC	Grouptypeind + transfoTE/EPCR&Dind + transfoTE/EPCR&Dind + transfoTE/EPCR&Dind + transfoTE/EPCR&Dind*commercialindTE/EPCcommercialT-racksBE/ABPCERNT-racksBE/ABPCERNT-racksBE/ABPR&Dind + transfoR&DT-racksBE/ABPR&Dind + transfoR&DT-racksR&Dind + transfoR&Dind - TE/EPCcommercialindTE/EPCcommercialindTE/EPCcommercialindTE/EPCCERN	Grouptypepolarityand + transfoTE/EPCR&D-45 kVand + transfoTE/EPCR&D20 kVand + transfoTE/EPCR&D4 kVand*commercialandTE/EPCcommercialandTE/EPCcommercialandTE/EPCcommercialandTE/EPCcommercialandTE/EPCcommercialandTE/EPCcommercialandTE/EPCcommercialandTE/ABPCERNT-racksBE/ABPCERNT-racksBE/ABPR&DT-racksR&D400/150 VT-racksR&D1andTE/EPCcommercialandTE/EPCcommercialandTE/EPCcommercialandTE/EPCcommercialandTE/EPCCERNandTE/EPCCERN	Responsible GrouptypeVoltage, polarityind + transfoTE/EPCR&D-45 kV0.2ind + transfoTE/EPCR&D20 kV0.2ind + transfoTE/EPCR&D4 kV2ind + transfoTE/EPCR&D4 kV2ind*commercial-40 kV0.2indTE/EPCcommercial-40 kV0.2TracksBE/ABPCERN+/- 30 V-T-racksBE/ABPCERN+/- 30 V-T-racksBE/ABPR&D+ 1 kV20ind + transfoR&D400 / 150 V20T-racksR&DindTE/EPCcommercial-indTE/EPCcommercial10indTE/EPCcommercial10indTE/EPCCERN20 kV2	$\begin{array}{c c c c c c c c c c c c c c c c c c c $	$\begin{array}{cccccccccccccccccccccccccccccccccccc$	$\begin{array}{c c c c c c c c c c c c c c c c c c c $	$\begin{array}{cccccccccccccccccccccccccccccccccccc$	$\begin{array}{cccccccccccccccccccccccccccccccccccc$	$\begin{array}{cccccccccccccccccccccccccccccccccccc$	$ \begin{array}{cccccccccccccccccccccccccccccccccccc$	Responsible GrouptypeVoltage, polarityLoaddurationdurationratefacility's test3 MeV tinac4Sparesind + transfoTE/EPCR&D-45 kV0.20.72-5201111ind + transfoTE/EPCR&D20 kV0.20.72-5201111ind + transfoTE/EPCR&D20 kV0.20.72-5201111ind + transfoTE/EPCR&D4 kV20.72-5201111ind *commercial-0.72-52011111ind *commercial-0.72-52011111ind *commercial-0.72-52011111ind *commercial-0.70.72-52011111ind *commercial-0.70.7cw111111111111111111111111111111111111111111111111	$ \begin{array}{cccccccccccccccccccccccccccccccccccc$	$ \begin{array}{cccccccccccccccccccccccccccccccccccc$





June 7th 2011

Linac4 ISWP J.L.

Summary

- WPIS review:
 - Resources presented by tasks representatives
 - LEBT completion realistic
 - IS-test stand completion + commissioning is challenging (delay).
 - Extraction simulation well under way, mandatory measurements will be available end of 2012.
 - Draft differential pumping design in progress, teething front end vacuum chamber and insulator (specification may have to be down graded).
- Risk:
 - Delay, design and production under high load
 - Technical: installing the pulsed power-front end in the 3MeV test stand will be challenging integration review as soon as all volumes are available (sept. 2011)
- L4 will only move after (successful) H⁻ tests
- Installing a new extraction system, new power supplies and a new source mid 2012 is challenging but leaves 5 month for debugging and commissioning of the prototypes *This is our baseline*.
- Resource estimate : xx FTE, xx FTE fellows, x.x MCHF (no contingency)

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Action plan August 2010, draft Schedule & Resources: *34 FTE, 4.5 MCHF*

Date	L4-IS 3 Me ^v test sta	V		-tunnel g. 400	U	4-IS	upgrades	sLHC P Generat sta	tor test	H- IS t	test star	nd	Cs Laboratory			
2010						Minimal dump, protons		RF and plasma diagnostics						Design		
2011	protons, mini H- pul	lse				Rev. world's IS Rev. WPIS june		Gas Dynamics, Upgrade to HT		0	Design, production					
2012						ultis dun	stage and np				Test and commissioning					
2013	Move to L4 building 40				·		IT-supply action			Operation			Surface source Proto.			
2014			Operatio Upgrade		ol Sp	Spare parts			Operat	Operation			Test of prototype			
2015										Move to 152	Move test stand to 152					
		mΥ	fraction	kCHF	hours]	Reso	urces' profile	е	2011	2011 2012		13	2014	2015	
total Manp	ower	33.9		I	J		Hardware	2.1 MCHF			ا ۹	┞───		†		
staff			60%	,	J		Design office	-	kCHF	1062	1637	958	8	494	336	
Fellows		13.6	40%, 36%	1632		fellows		1.6 MCHF		24%	36%	219	%	11%	7%	
		 '	+ +	-	15500	-			FTF						2.8	
		 '	46%			4									2.0 8%	
				4487		J				23/0	3370	227	/0			
FSU+MM hardware total cost	e		18% 46%	791 2064 4487	15500	-		3 FTE .6 FTE	FTE	7.9 23%	36% 11.1 33%	7.4 229	4	11% 4.7 14% 32	2 8	